

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|---|-------|------------------|---------|------------------|
| L1 | 71 | (((controlled or assisted) near growth) same crystalline) | USPAT | OR | OFF | 2004/12/08 13:45 |
| L2 | 42 | "5eV" | USPAT | OR | OFF | 2004/12/08 13:35 |
| L3 | 0 | 2 and 1 | USPAT | OR | OFF | 2004/12/08 13:33 |
| L4 | 15 | ((crystalline near growth) or (growth near3 crystalline)) same "eV" | USPAT | OR | OFF | 2004/12/08 13:36 |

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|-------|--------|--|-------|------------------|---------|------------------|
| L1 | 35773 | ((manufacturing or fabricating or making) same ((energy near storage near device) or battery or (fuel near cell) or capacitor)) | USPAT | OR | OFF | 2004/12/08 11:32 |
| L2 | 79700 | depositing same (film or layer) | USPAT | OR | OFF | 2004/12/08 11:33 |
| L3 | 5099 | 2 and 1 | USPAT | OR | OFF | 2004/12/08 11:33 |
| L4 | 195 | energized near ions | USPAT | OR | OFF | 2004/12/08 11:36 |
| L5 | 7 | 4 and 3 | USPAT | OR | OFF | 2004/12/08 11:36 |
| L6 | 136389 | ("PACD" or "IAD" or "PD" or (plasma near assisted near chemical near vapor near deposition) or (ion near assisted near deposition) or (physical near vapor near deposition) or sputtering) | USPAT | OR | OFF | 2004/12/08 12:05 |
| L7 | 2147 | 3 and 6 | USPAT | OR | OFF | 2004/12/08 12:06 |
| L8 | 61 | ((assist\$4 near growth) or (control\$4 near growth)) same ((crystal or crystalline) near structure) | USPAT | OR | OFF | 2004/12/08 12:19 |
| L9 | 1 | 7 and 8 | USPAT | OR | OFF | 2004/12/08 12:07 |
| L10 | 56 | 2 and 4 | USPAT | OR | OFF | 2004/12/08 12:25 |
| L11 | 8292 | (204/192.1-192.38.ccls. or 204/298.01-298.41.ccls.) | USPAT | OR | OFF | 2004/12/08 12:28 |
| L12 | 119 | 1 and 11 | USPAT | OR | OFF | 2004/12/08 12:28 |